L Number	Hits	Search Text	DB	Time stamp
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-	116	(700/121.ccls. not 700/109,110.ccls.) and (determin\$3 same	USPAT;	2004/10/30 10:21
	207	yield)	US-PGPUB	
-	327	(700/121.ccls. not 700/109,110.ccls.) and yield	USPAT;	2004/10/30 10:21
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-	211	((700/121.ccls. not 700/109,110.ccls.) and yield) not ((700/121.ccls. not 700/109,110.ccls.) and (determin\$3 same	USPAT;	2004/10/30 10:25
		yield))	US-PGPUB	
	301	determin\$3 with yield with loss	LICDAT.	2004/40/20 40:24
-	301	determinas with yield with loss	USPAT; US-PGPUB	2004/10/30 10:31
_	35	determin\$3 with yield with loss same (semiconductor or wafer)	USPAT;	2004/10/30 10:31
	33	determines with yield with loss same (semiconductor or water)	US-PGPUB	2004/10/30 10.31
<u> </u>	5	"6367040"	USPAT;	2004/10/30 10:51
			US-PGPUB	2004/10/30 10.31
-	16	("4801869"   "5355212"   "5438527"   "5598341"   "5754432"	USPAT	2004/10/31 09:00
		"5761064"   "5777901"   "5787190"   "5822218"   "5828778"	00.7	200 17 10/01 00:00
		"5940300"   "5943437"   "6016562"   "6017771"   "6061814"		
		"6169960").PN.		
-	4	("3751647"   "5544256"   "5777901"   "6265232").PN.	USPAT	2004/10/31 09:08
-	192	kill adj2 ratio	USPAT;	2004/10/31 09:30
			US-PGPUB	
-	0	kill adj2 ratio same calibrat\$3	USPAT;	2004/10/31 09:30
į			US-PGPUB	
-	13	kill adj2 ratio and calibrat\$3	USPAT;	2004/10/31 09:32
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-	7	kill adj2 ratio same weight\$3	USPAT;	2004/10/31 10:33
	<u> </u>	viold with important with pullback (0.20). Control	US-PGPUB	000444045
-	0	yield with impact with calibrat\$3 with factor	USPAT;	2004/10/31 11:33
_	14	yield same impact same calibrat\$3 same factor	US-PGPUB	2004/40/24 40:24
-	1-4	yield same impact same calibratos same factor	USPAT;	2004/10/31 10:34
_	142	kill adj2 ratio and weight\$3	US-PGPUB USPAT;	2004/10/31 10:42
	172	Nill daja tatio and weightwo	US-PGPUB	2004/10/31 10:42
-	3	yield adj2 loss and calibration adj2 factor	USPAT;	2004/10/31 10:57
		justice and contraction days rector	US-PGPUB	2007/10/31 10:0/
-	139	defect with excursion	USPAT;	2004/10/31 10:47
	1		US-PGPUB	
-	0	defect with excursion with limit	USPAT:	2004/10/31 10:47
			US-PGPUB	
-	3	defect with excursion same calibrat\$3	USPAT;	2004/10/31 10:51
			US-PGPUB	
-	18	defect with calibrat\$3 with factor	USPAT;	2004/10/31 10:52
			US-PGPUB	
-	359	yield adj2 loss and calibrat\$3	USPAT;	2004/10/31 10:57
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Merino, M.A.; Cruceta, S.; Garcia, A.; Recio, M.;

Advanced Semiconductor Manufacturing Conference and Workshop, 2000

IEEE/SEMI , 12-14 Sept. 2000

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Patterson, O.D.; Hansen, M.H.;

Semiconductor Manufacturing, IEEE Transactions on , Volume: 15 , Issue: 4 , Nov. 2002

Pages: 404 - 410

[Abstract] [PDF Full-Text (517 KB)] IEEE JNL

### 2 The impact of tolerance on kill ratio estimation for memory

Patterson, O.D.; Hansen, M.H.;

Advanced Semiconductor Manufacturing Conference and Workshop, 2000

IEEE/SEMI , 12-14 Sept. 2000

Pages: 175 - 180

[Abstract] [PDF Full-Text (488 KB)] IEEE CNF

# 3 Critical area based yield prediction using in-line defect classification information [DRAMs]

Segal, J.; Sagatelian, A.; Hodgkins, B.; Ben Chu; Singh, T.; Berman, H.; Advanced Semiconductor Manufacturing Conference and Workshop, 2000 IEEE/SEMI , 12-14 Sept. 2000

Pages:83 - 88

[Abstract] [PDF Full-Text (508 KB)] IEEE CNI

# 4 Evaluation of the yield impact of epitaxial defects on advanced semiconductor technologies

Williams, R.; Jacques, R.; Akbulut, M.; Wayne Chen; Advanced Semiconductor Manufacturing Conference and Workshop, 2000 IEEE/SEMI, 12-14 Sept. 2000 Pages:1 - 7

[Abstract] [PDF Full-Text (528 KB)] IEEE CNI

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## **5 SmartBit<sup>TM</sup>: bitmap to defect correlation software for yield improvement**

Merino, M.A.; Cruceta, S.; Garcia, A.; Recio, M.;

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IEEE/SEMI, 12-14 Sept. 2000

Pages: 194 - 198

[Abstract] [PDF Full-Text (372 KB)] IEEE CNF

# 6 Key considerations in the development of defect sampling methodologies

McIntyre, M.; Nurani, R.K.; Akella, R.;

Advanced Semiconductor Manufacturing Conference and Workshop, 1996. ASMC 96 Proceedings. IEEE/SEMI 1996, 12-14 Nov. 1996

Pages:81 - 85

[Abstract] [PDF Full-Text (484 KB)] IEEE CNF

## 7 Limitations to estimating yield based on in-line defect measurements

Riley, S.L.;

Defect and Fault Tolerance in VLSI Systems, 1999. DFT '99. International Symposium on , 1-3 Nov. 1999

Pages: 46 - 54

[Abstract] [PDF Full-Text (132 KB)] IEEE CNF

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